



15W 17628  
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Paul B. Mirkarimi et al.                      Docket No. : CIL-10972  
Serial No. : 10/086,614                                      Art Unit : 1762  
Filed : March 1, 2002                                      Examiner : W. Markham  
For : Ion-Assisted Deposition Techniques For  
The Planarization Of Topological Defects

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

CERTIFICATE OF MAILING UNDER 37 CFR 1.8(a)

I hereby certify that the *attached* correspondence comprising:

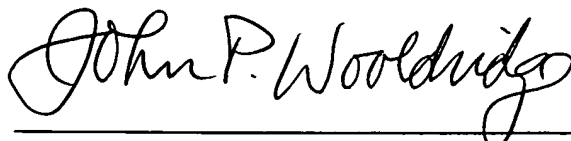
1. Amendment (3 pages);
2. Petition for Extension (in duplicate);
3. Certificate of Mailing; and
4. Return Postcard;

is being deposited with the United States Postal Service as first class mail in an envelope addressed to:

Mail Stop Amendment  
Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

on June 21, 2006

John P. Wooldridge  
(Type or print name of person mailing paper)

  
(Signature of person mailing paper)